

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Jin Zhao et al. Confirmation No.: 4854
Application Number : 10/623,757
Filed : July 21, 2003
Title : MAINTAINING A REACTOR CHAMBER OF A CHEMICAL VAPOR DEPOSITION SYSTEM
TC/Art Unit : 1792
Examiner: : Francis P. Smith

Docket No. : TI-35855 (0025.0220)
Customer No. : **23494**

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

REPLY TO OFFICE ACTION

In reply to the Office Action mailed October 3, 2008, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks/Arguments follow the amendment sections of this paper.